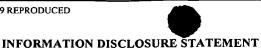
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ATTORNEY DOCKET NO. 3194.1026-006

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FIRST NAMED INVENTOR Jeffrey J. Spiegelman FILING DATE 6/21/05

February 1, 2005

IN AN APPLICATION

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EXAMINER Carrillo

CONFIRMATION NO. GROUP 1792

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DT05 Rec'd PCT/PTQ 2 1 FEB 2 1 Sheet 2 of 4

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FIRST NAMED INVENTOR Jeffrey J. Spiegelman

3194.1026-006

FILING DATE 6/21/05

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Jeffrey J. Spiegelman

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6/21/05

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